

Effect of Annealing Temperature on Structural, Morphological, Optical and Electrical Properties of Spray Deposited V₂O₅ Thin Films

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Nanostructured vanadium pentoxide (V₂O₅) thin films have been deposited by a simple and cost-effective spray pyrolysis technique (SPT) at substrate temperature 300 °C and post annealed at atmospheric conditions in the temperature range from 300 °C to 500 °C at a constant rate of heating. The influence of post annealing heat treatment on the crystallization of V₂O₅ has been investigated. Films were characterized structurally by X-ray diffraction, morphologically by Scanning electron microscopy, optically using UV-Vis spectrophotometer, electrical characterization using Hall probe and Raman spectroscopy has been carried out for phase confirmation. X-ray diffraction analysis (XRD) revealed that, as deposited films were orthorhombic structures with a preferential orientation along (0 0 1) direction. Moreover, it was observed that crystallite size increases from 22 nm to 56 nm with increase in annealing temperature. Optical properties of these samples were studied in the wavelength range 300–1000 nm. Raman spectrum confirms the layered structure of V₂O₅ thin films. Hall Effect measurements indicate that the change in carrier concentration with increase in annealing temperature.

Keywords: V₂O₅, annealing temperature, Raman spectroscopy, carrier density.

1. INTRODUCTION

Vanadium pentoxide (V₂O₅) is the most stable phase in V-O system and it also exhibits multivalency, layered structure, wide optical band gap with good electrochemical and thermo chromic properties [1]. Especially, V₂O₅ in thin film form has attracted considerable interest due to their wide range of applications. Compared to bulk, V₂O₅ in nano thin film form substantially improve the performance of devices for energy storage and sensing due to their distinct physical and chemical properties because of their large surface area and with unique morphology [2]. The V₂O₅ thin films have been prepared by different techniques such as RF-sputtering [3], dc-magnetron sputtering [4], flash evaporation [5], spin coating [6], dip coating [7] and pulsed laser deposition [8]. However, a technique with a relatively low cost, good stoichiometry and large area, the spray pyrolysis has been used to prepare V₂O₅ thin films.

In the previous work [9], we have undertaken an extensive study of sprayed V₂O₅ thin films, i.e., optimization of the growth parameters, chemical composition, microstructural and optical properties. Annealing temperature critically effects the crystallinity and other material properties of the as deposited films. When the films are annealed, three processes may take place; recovery, recrystallization and grain growth. To study the effect of annealing temperature, as deposited films are treated at different annealing temperatures. This research deals with the effect of annealing temperature on

microstructural, optical and electrical properties of V₂O₅ thin films.

2. EXPERIMENTAL DETAILS

Ultrasonically cleaned glass substrates (Blue star, India) were used to deposit V₂O₅ thin films with optimized parameters (Nozzle to substrate distance (NSD) = 30 cm, substrate temperature (T_s) = 300 °C, 0.1 M of ammonium vanadate and water as solvent) has been chosen for annealing treatment. This film was treated at different annealing temperatures such as 300 °C, 400 °C and 500 °C per one hour at a constant rate of heating 5 °C/min.

To examine the crystalline structure of the films, Bruker D8 Advance, USA X-ray diffractometer (XRD) using Cu K_α radiation ($\lambda = 1.54059 \text{ \AA}$) was employed. The absorbance spectra of all the films were recorded by a UV-Vis 3000 spectrophotometer, Lab India Analytical Instruments. Raman scattering spectra were recorded at room temperature using Renishaw In Via micro Raman spectrometer in the wave number range 100–1000 cm⁻¹ with a 532 nm laser. The surface morphology of the films was observed with scanning electron microscope (Carl ZEISS EVO 18, Germany). Carrier density and resistivity were measured with Hall Effect measurement system (HMS-3000, ECOPIA) under a magnetic field of 0.5 T at room temperature.

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3. RESULTS AND DISCUSSION

All the as deposited and annealed films were pin hole free. Adhesion of the film was tested with scotch tape and found to well adhered to substrates. Thickness of the films were found to be 950 nm.

Fig. 1 shows the X-ray diffraction (XRD) patterns of V_2O_5 thin films annealed at different temperatures (T_a) and as deposited V_2O_5 films were found to be polycrystalline nature. The peaks observed at $2\theta = 15.3^\circ, 20.2^\circ, 26.1^\circ, 30.9^\circ, 41.1^\circ, 51.1^\circ$ were corresponding to (200), (001), (110), (301), (002) and (020) planes respectively. This pattern confirmed the formation of single phase V_2O_5 films with orthorhombic structure and well-defined layered structure and agreed with the JCPDS Card No. 89–2482. After annealing the films, the intensity of the (0 0 1) peak found to decrease with annealing temperatures to 500 °C and the intensity of (110) peak increased at the same time. This might be due to the recrystallization process triggered by the increased annealing temperature. This could be corroborated from the appearance of new peaks (200), (301), (111) and (112) reflections for the films annealed at different temperatures [10]. Crystallite size of the films was estimated using Sherrer's equation; it is observed that crystallite size increases with increase in annealing temperature. The values of crystallite sizes for different annealing temperatures are shown in Table I. The increase in crystallite size may be due to the coalescence process that takes place by annealing the films [11].

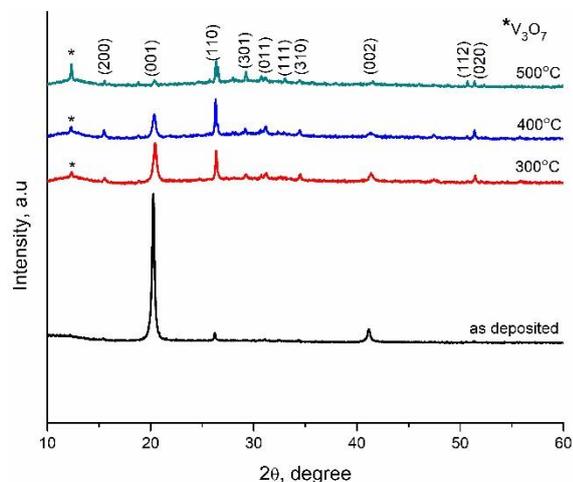


Fig. 1. XRD patterns of V_2O_5 thin films at different annealing temperatures

Table 1. Crystallite sizes of V_2O_5 thin films annealed at different temperatures

Annealing temperature, °C	Crystallite size, nm
As deposited	22
300	39
400	46
500	56

SEM images of V_2O_5 thin films annealed at different temperatures are given in Fig. 2. As deposited V_2O_5 film shows the formation of fiber like morphology (Fig. 2 a). As the annealing temperature was increased, the width of the fiber like structure (Fig. 2 b) began to disappear.

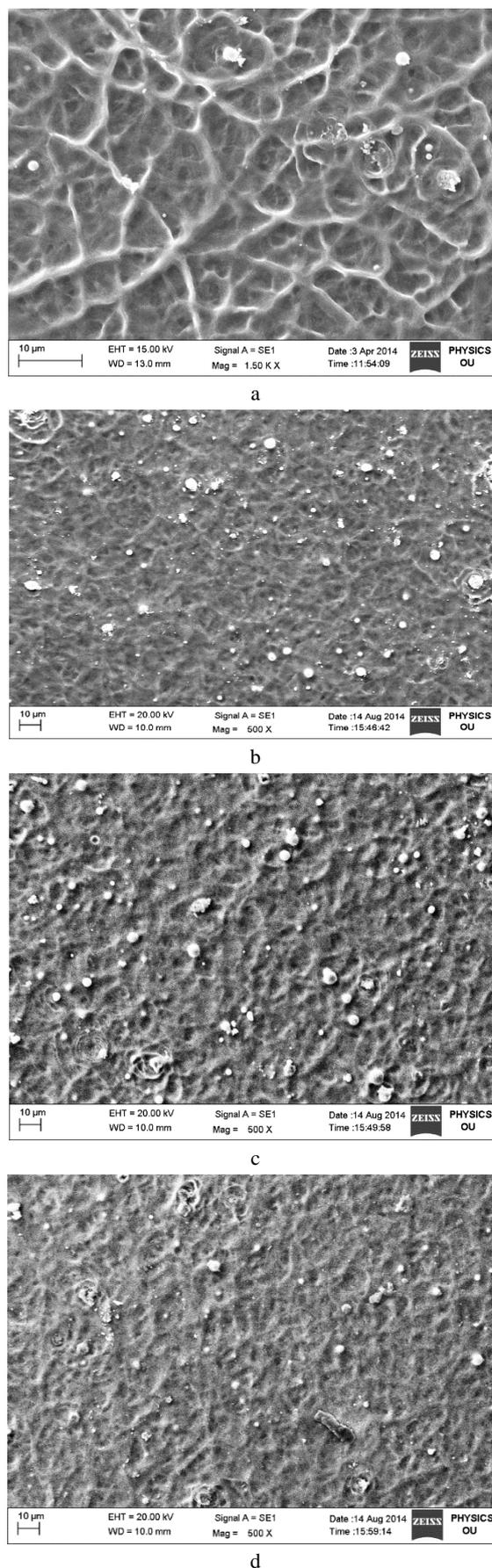


Fig. 2. SEM images of V_2O_5 films deposited at different annealing temperatures: a – as deposited; b – 300 °C; c – 400 °C; d – 500 °C

At higher annealing temperatures (Fig. 2 d), the fibers disappeared due to the recrystallization of the material. The Raman spectra of V_2O_5 films annealed at different temperatures are shown in Fig. 3.

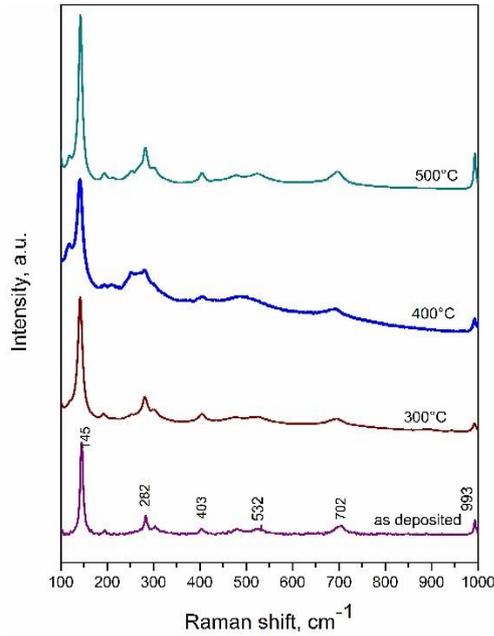


Fig. 3. Raman spectra of V_2O_5 films deposited at different annealing temperatures

From the spectra, it can be seen that structural properties of the films vary with the annealing temperatures. A spectrum of the deposited films is more intense and sharper due to the crystalline nature.

As the annealing temperature increases, the bands observed were broadened and shifted. This may be due to the structural reorganization of the film. All observed bands are assigned and tabulated in Table 2 [12].

Table 2. Assignment of Raman bands

Raman bands, cm^{-1}	Assignment
145	The skeleton bent vibration, evidence for the layer-type structure
282	Bending vibrations of the O_C-V-O_B bond
403	The bending vibration of $V-O_B-V$ bond
532	stretching vibration of the $V-O_B$
702	Stretching vibration of $V-O_C$
993	Terminal oxygen ($V=O$) stretching mode

These bands show perfect evidence of the formation layer structure of V_2O_5 thin films.

The optical absorbance spectra of the films as deposited and annealed at different temperatures are shown in Fig. 4. The absorbance was found to increase with an increase in the annealing temperature and annealed films showed a high absorbance which indicated the formation of structural reorganization with an increase in grain size [13]. The direct band gap (E_g) of the films was calculated from the extrapolation of the linear part of the $(\alpha h\nu)^2$ versus $h\nu$ curve to zero (Fig. 5). The calculated values of the optical band gap (E_g) were 2.4 eV, 2.31 eV, 2.25 eV and 2.14 eV for the films as deposited and annealed at different temperatures 300 °C, 400 °C and 500 °C respectively.

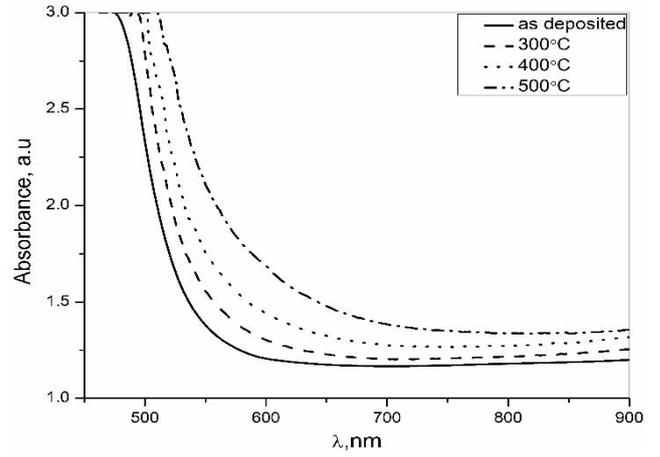


Fig. 4. Absorbance of the V_2O_5 films with wavelength for different annealing temperatures

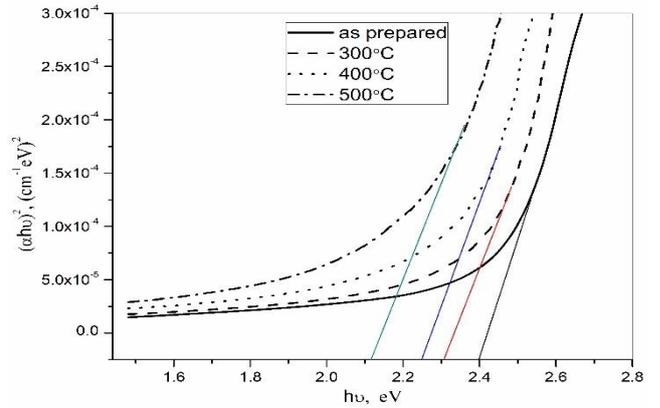


Fig. 5. $(\alpha h\nu)^2$ v/s $h\nu$ at different annealing temperatures

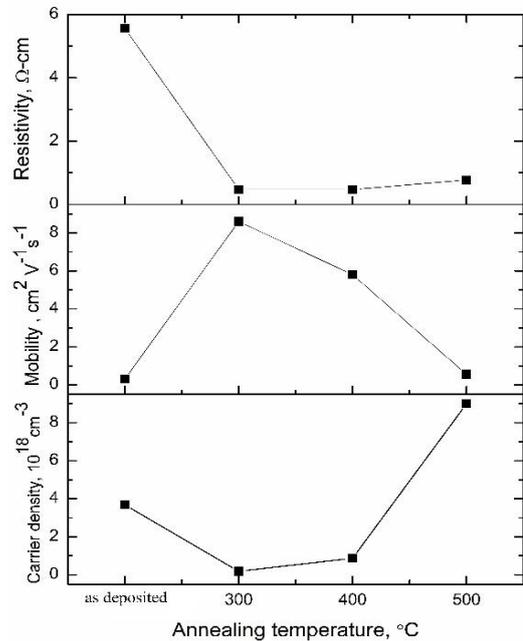


Fig. 6. The resistivity, carrier mobility and density of the V_2O_5 films

When the film was annealed at higher temperature, the energy gap is shifted to lower photon energy and it clearly indicates that the energy gap decreases as the annealing temperature increases. The microstructure changes caused by annealing treatment can be attributed to decrease in

optical band gap. Similar observations are reported in V₂O₅ films deposited by dip coating technique [14], it can also be explained in terms of quantum-size effect in which the films with large size crystallites. The electrical properties of the films as deposited and annealed at different temperatures of V₂O₅ thin films measured by van der Pauw Hall measurement system are shown in Fig. 6.

4. CONCLUSIONS

V₂O₅ thin films have been synthesized by a simple spray pyrolysis technique. As deposited films exhibited an orthorhombic structure with fiber like morphology. The optical band has decreased with increasing annealing temperature. The morphology of the thin films has been varied with an increase in the annealing temperature. The carrier density and resistivity have been varied with an increase in the annealing temperatures.

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